



AR Glass



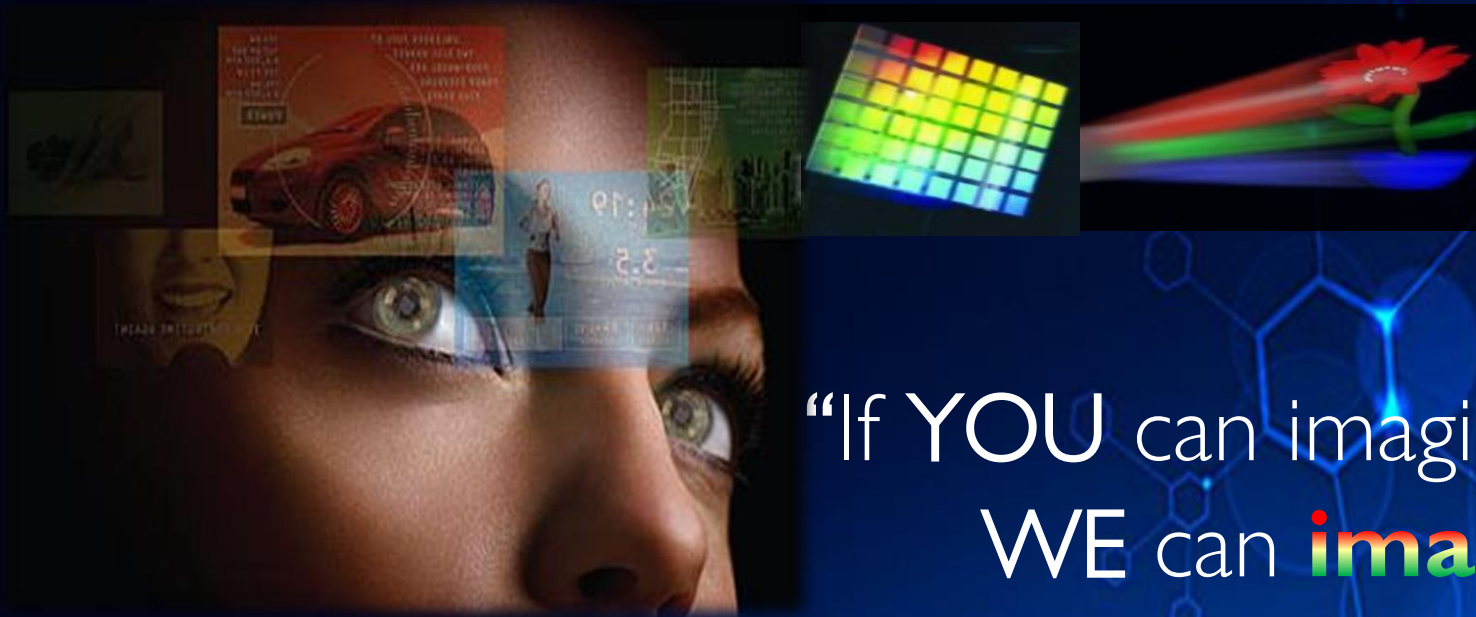
Sensing Device



Bio Chip



Holography

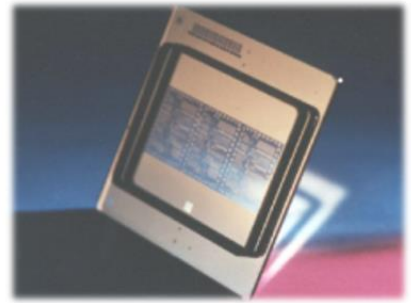


“If YOU can imagine it,
WE can **image** it”

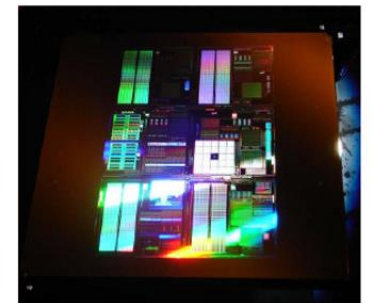
Toppan Photomask Co., Ltd. (TPC)

The world's premier provider of photomasks for semiconductors

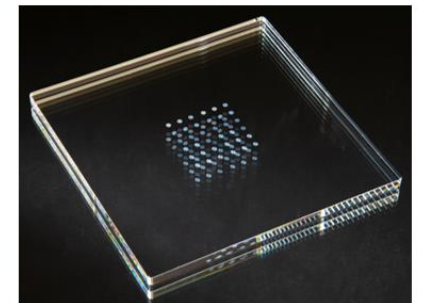
■ Company Name	Toppan Photomask Co., Ltd.
■ Location	HQ Tokyo
■ Business start	April 1 st , 2022
■ President	Teruo Ninomiya
■ Shareholders	Toppan Inc. 50.1% Integral Corporation 49.9%
■ Headcount	1,800 (as of April 1 st , 2022)
■ Locations	8 manufacturing facilities in key geographical locations



DUV reticle/photomask
Transmissive Mask Lithography



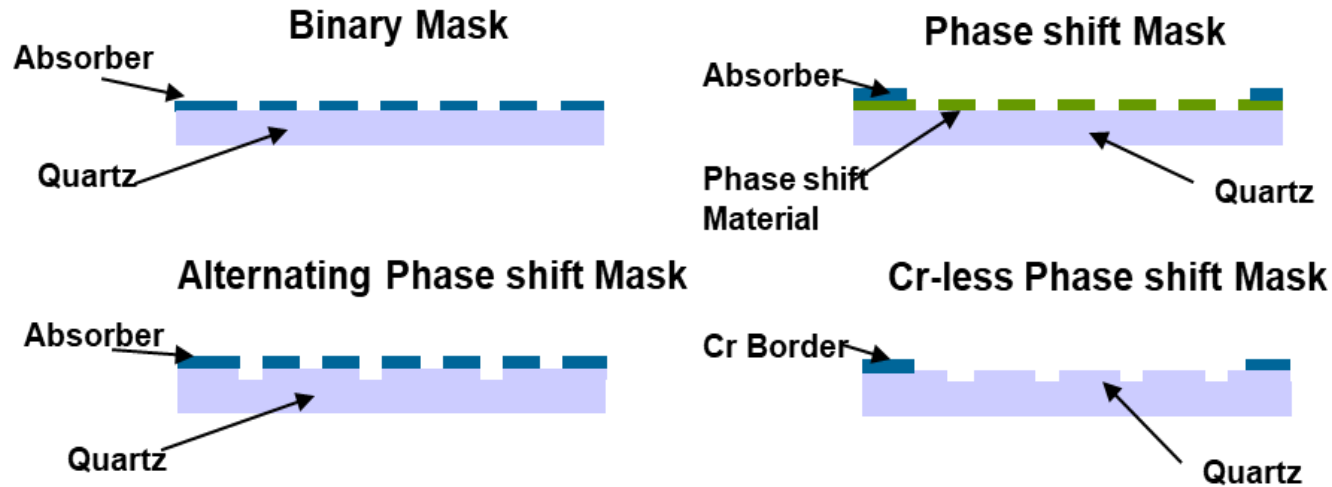
EUV Mask
Reflective Mask Lithography



Nano Imprint Lithography master
Imprint Lithography

Photomasks and NIL Masters

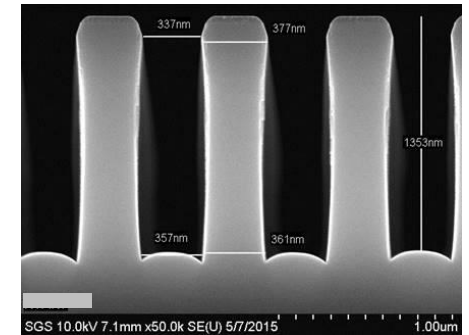
- Quartz-etched patterns are also used for projection lithography photomasks
- Same technology used to manufacture NIL masters



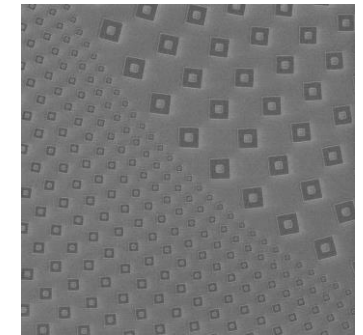
quartz etched products are running HVM



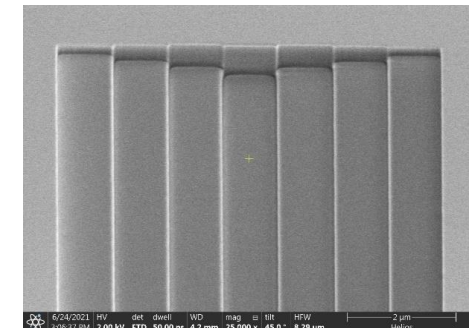
Deep-etch Quartz gratings
(e.g. laser applications)



MetaLenses
(e.g. flat optics)

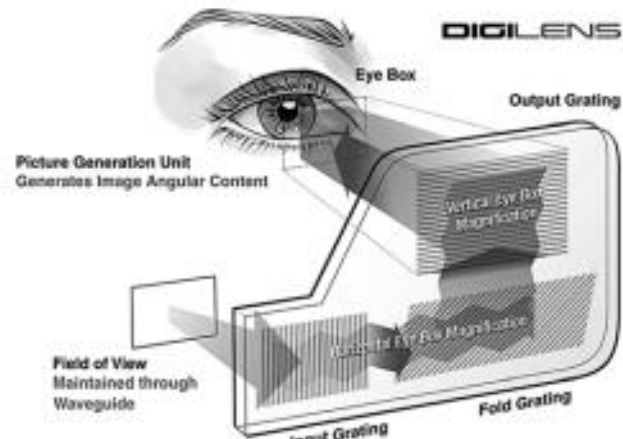


Multi-level gratings
(e.g. NIL master for AR glasses)



NIL Master Requirements

AR/VR Devices



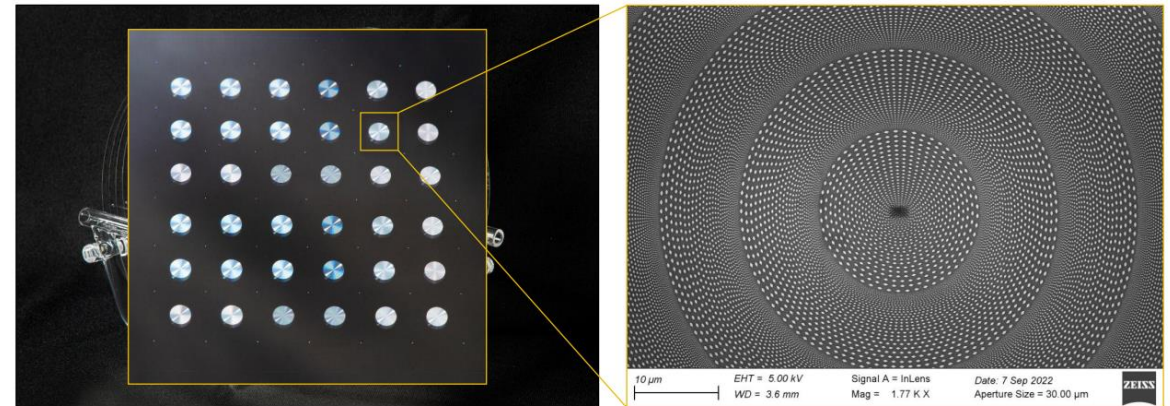
B.C. Kress, I. Chatterjee „Waveguide combiners for mixed reality headsets“ de Gruyter, Nanophotonics 10/2021

Consist of gratings that require:

- L/S gratings of arbitrary orientations
- Precise accuracy of orientation angle
- Minimal periodic placement errors
- Non-vertical Grating profiles
- Various etch depths within one grating

Metalens-based Optics

EVG Nanoimprint Lithography | Metalenses - Process Results



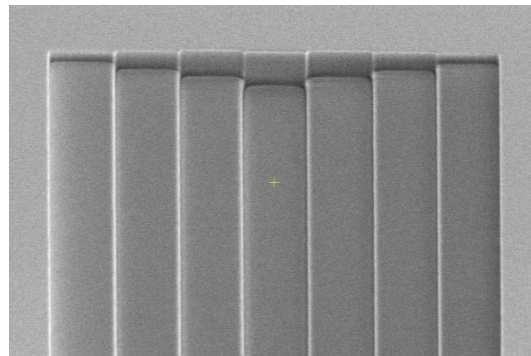
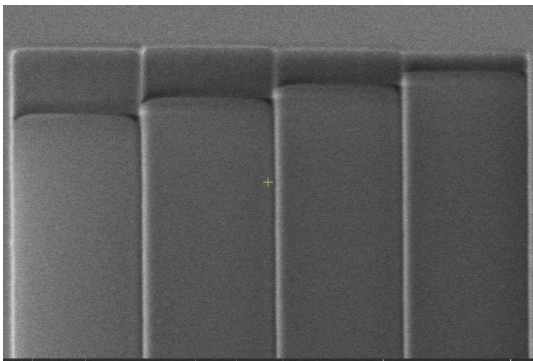
- High resolution
- Meta-atoms of arbitrary shapes and orientations

→ Our applied Photomask technology is the enabler of these new segments!

Staircase Gratings & 3D Pattern

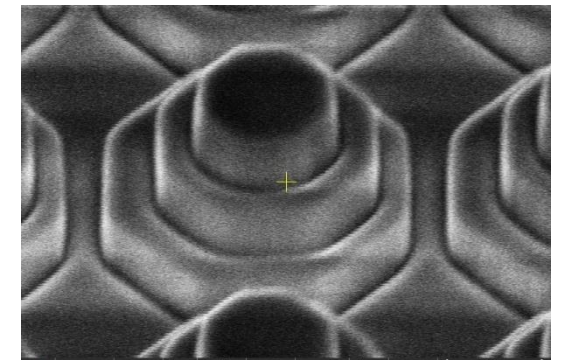
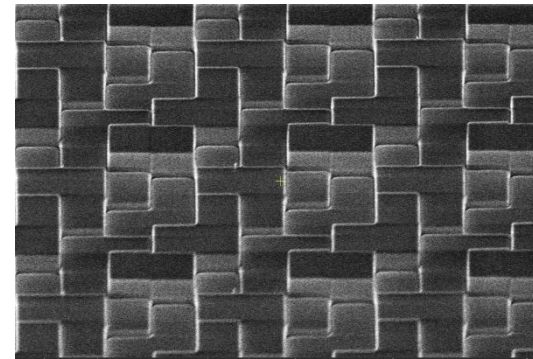


- Staircase is an option for non vertical profiles
 - discrete steps of various widths and depths



Preliminary samples

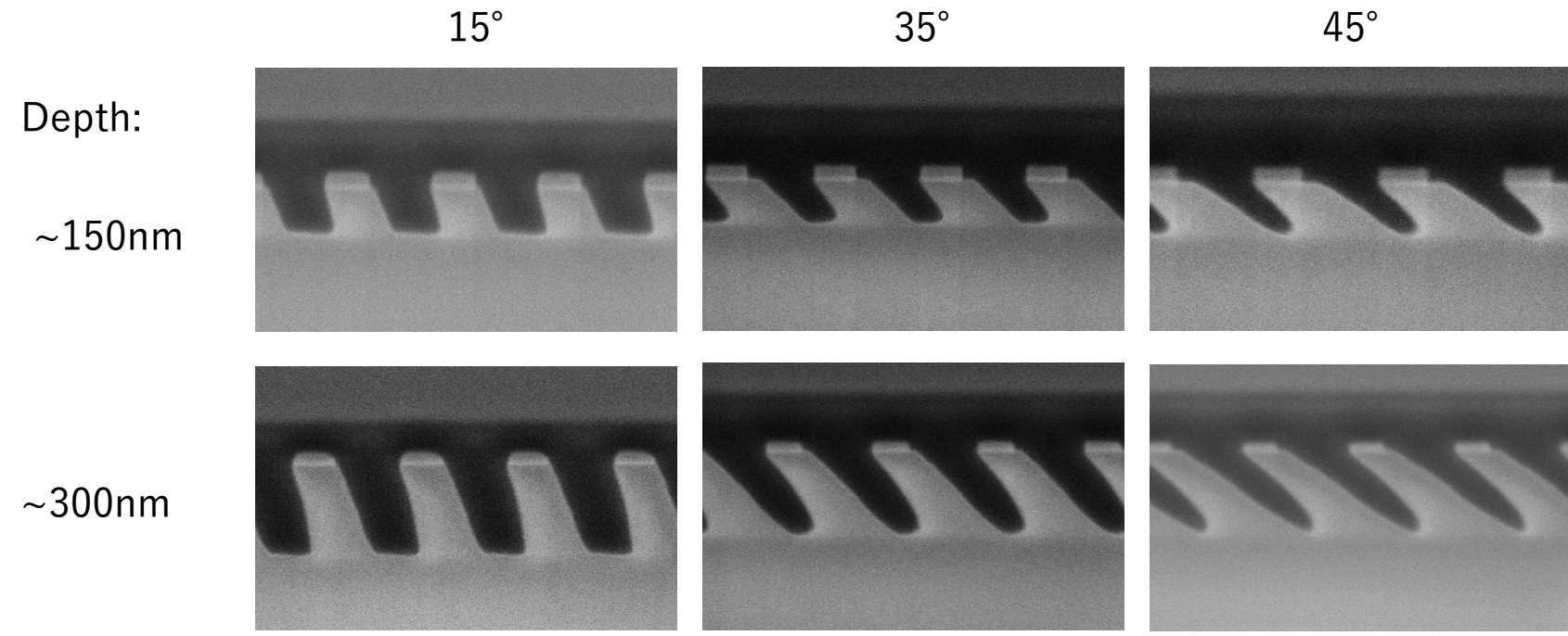
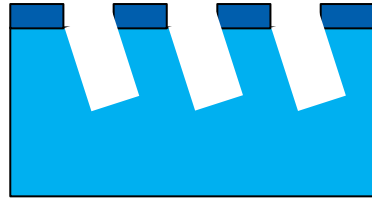
- 3D pattern for other optical applications



Preliminary samples

Slanted Gratings

- AR/VR Gratings typically require non-vertical profiles

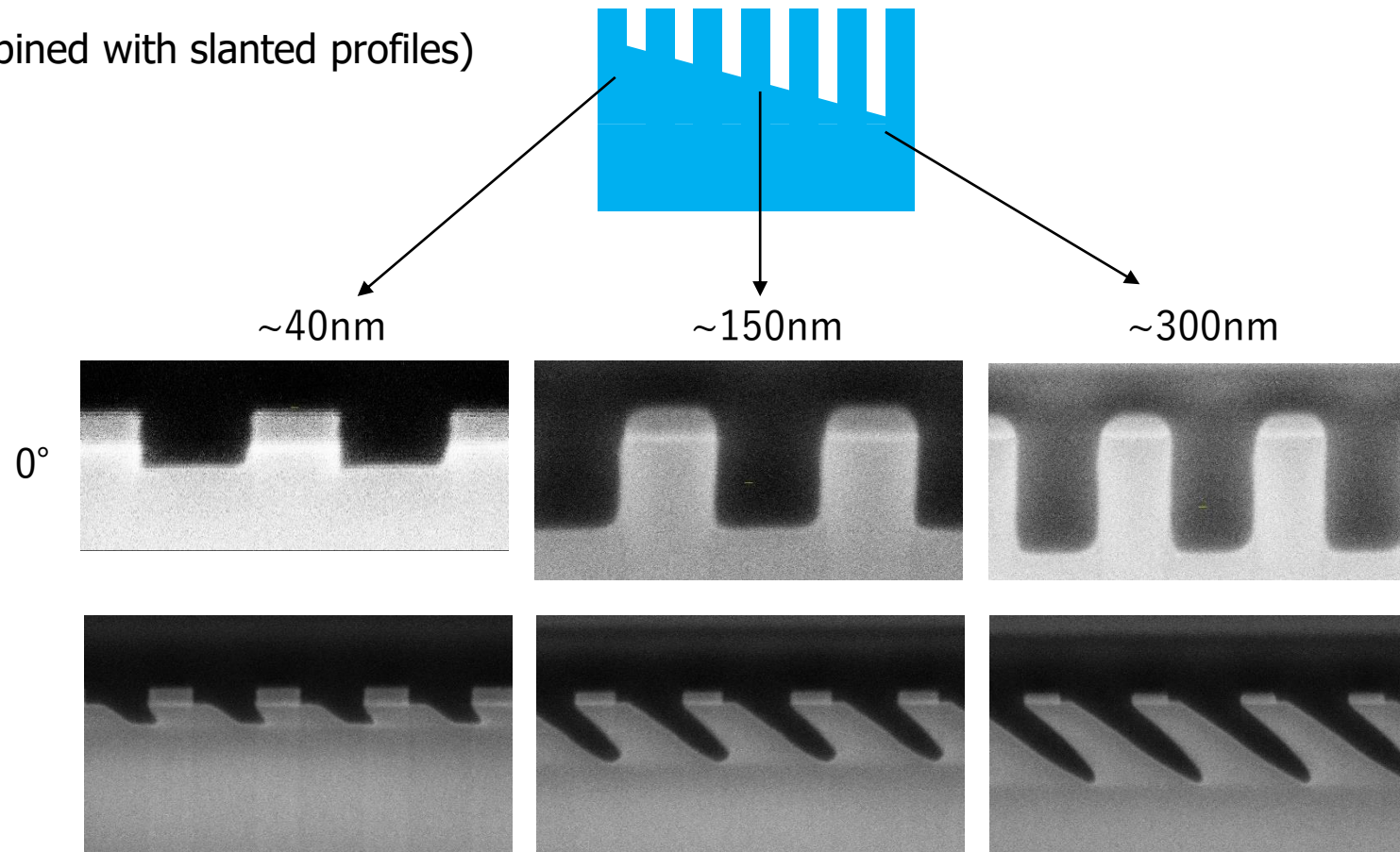


150nm 1:1 Lines/Space
(HM still on top)

Varying Etch Depth

- Gratings can require various etch depths

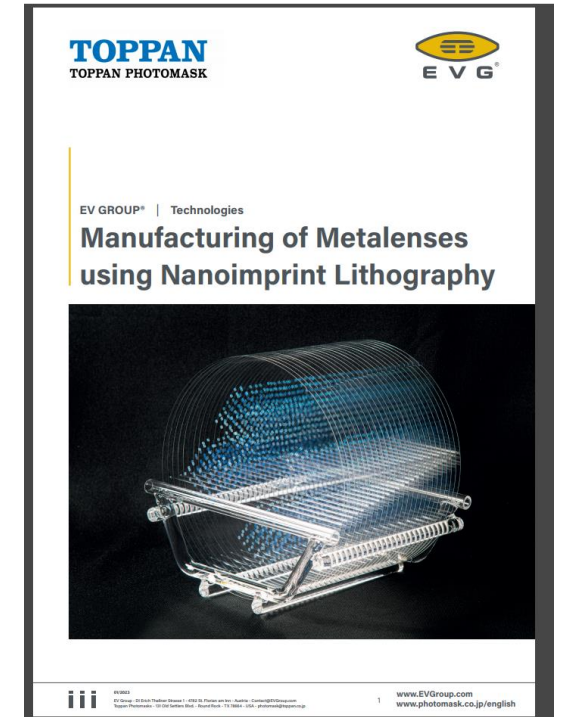
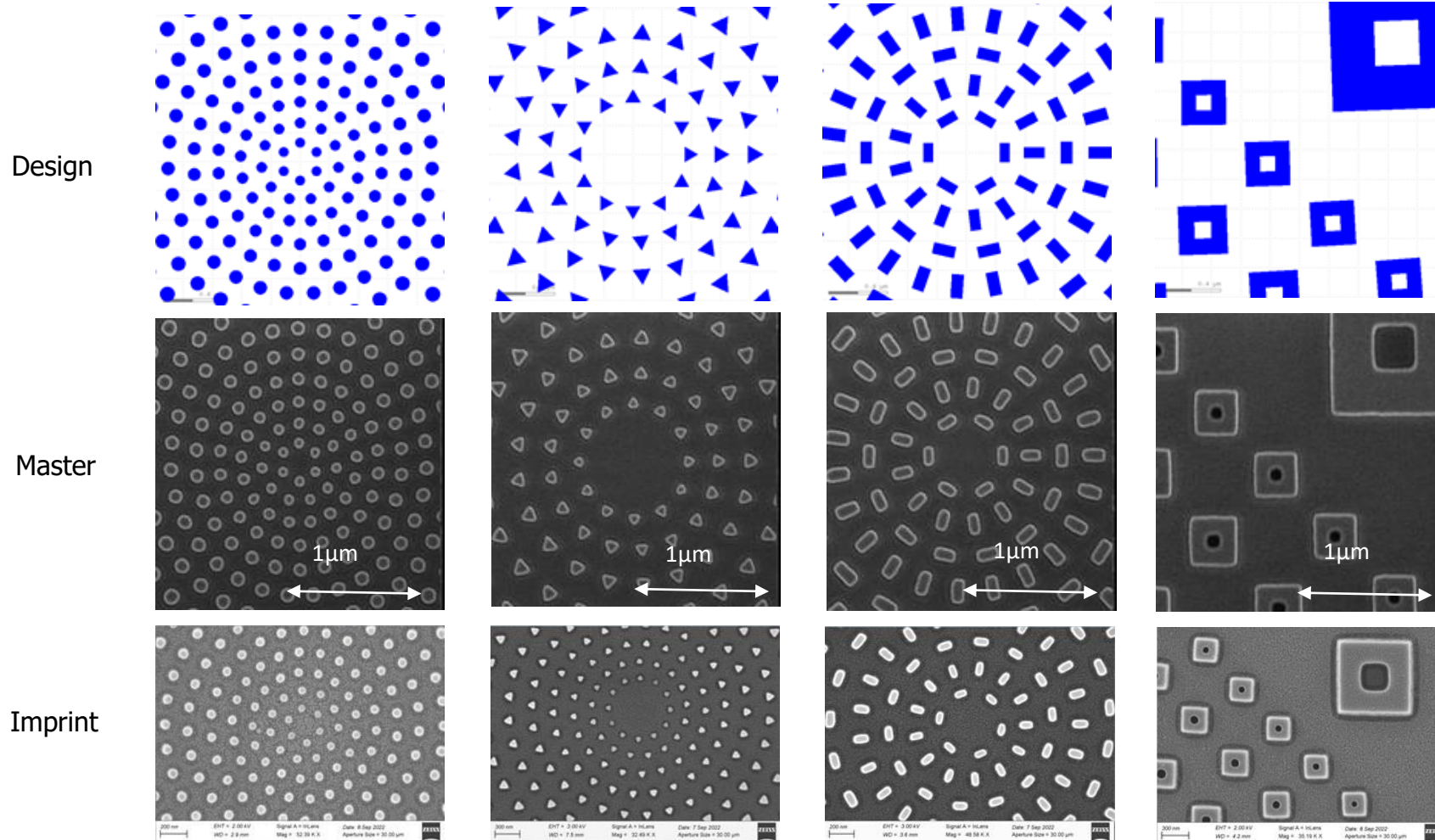
(maybe combined with slanted profiles)



150nm 1:1 Lines/Spaces
(HM still on top)

Meta-atoms of arbitrary Shapes

- NIL masters with meta-atoms of arbitrary shapes at high resolution can be manufactured
- NanoImprint can accurately reproduce these shapes by EVG tools



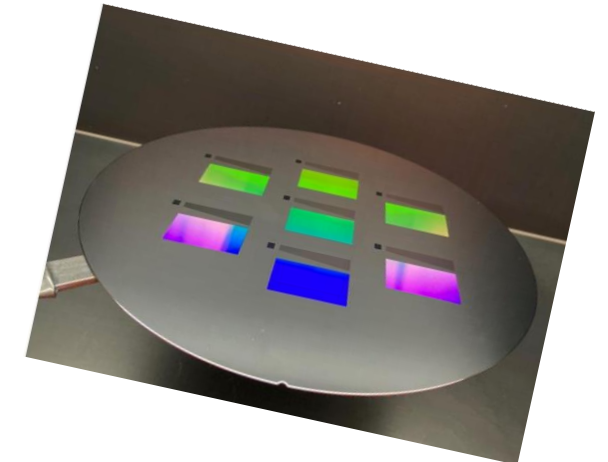
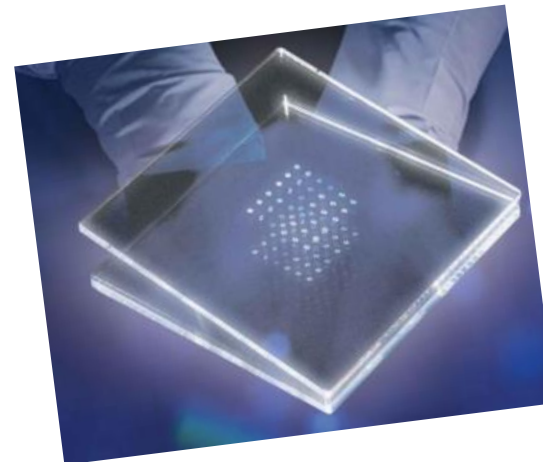
Joint White Paper Toppan & EVG illustrates availability of processes/tools for high-volume manufacturing of metalenses using NIL

Summary

→ Photomask technology is well suited to manufacture NIL masters for advanced optical devices

Our Offer:

- Industrialized setup for prototypes and high-volume manufacturing of masters
- Excellent understanding & implementation of special requirements of NIL masters
- Access to high production and e-beam capacity
- Tightly controlled manufacturing processes and defect-free environment
- 6" square Quartz and 8" round Silicon form factors



TOPPAN
TOPPAN PHOTOMASK

Toppan's industrialized, state of the art technology will bring Your cutting-edge products into reality

We look forward to a
Bright Future with you

For more information, please contact us

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